

United States Patent and Trademark Office

COMMISSIONER FOR PATENTS
UNITED STATES PATENT AND TRADEMARK OFFICE
WASHINGTON, D.C. 2023I
WWW.USPIO.GOV

BIBDATASHEET

Bib Data Sheet

CONFIRMATION NO. 4653

SERIAL NUMBE 10/628,601	R	FILING DATE 07/28/2003 RULE	CLASS 438	GROUP AF 2812	_	D	ATTORNEY OCKET NO. 1692-73091		
APPLICANTS									
Michael J. Berman, Portland, OR;									
George E. Bailey, Welches, OR; Rennie G. Barber, Gresham, OR;									
** CONTINUING DATA **********************************									
FOREIGN APPLICATIONS ************************************									
Foreign Priority Claimed 35 USC 119 (a-d) cond met Verified and Acknowledged			STATE OR COUNTRY	SHEETS DRAWING 2	3 CLA	TAL MMS 7	INDEPENDENT CLAIMS 1		
ADDRESS LSI Logic Corporation 1551 McCarthy Blvd. Milpitas, CA 95035									
TITLE Method and apparatus for detecting backside contamination during fabrication of a semiconductor wafer									
	-	D All Fe				ees Fees (Filling)			
l N	LING FEE FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT time)						ees (Processing Ext. of		
RECEIVED N 750	lo	for following:			☐ 1.18 Fees (Issue) ☐ Other ☐ Credit				